



# 1st CEPHONA Workshop on Microscopic Characterisation of Materials and Structures for Photonics

Warsaw, November 24, 2003

## PROGRAM

- 9:55-10:00**    **Opening**
- 10:00-10:45**    **J.L. Weyher (Univ. of Nijmegen, The Netherlands)**  
Defect-selective etching of III-V and wide gap  
semiconductors
- 10:45-11:30**    **M. Leszczyński (Unipress, Warsaw)**  
X-ray diffraction and reflectivity in semiconductor  
industry and research
- 11:30-12:00**    **Coffee Break**
- 12:00-12:45**    **F. Phillipp (MPI-MF, Stuttgart, Germany)**  
Transmission electron microscopy of optoelectronic  
materials – basics and advanced methods
- 12:45-13:30**    **J. Kącki (ITE, Warsaw)**  
Electron microscopy of advanced optoelectronic  
structures
- 13:30-14:30**    **Lunch break**
- 14:30-17:00**    Laboratory training in TEM specimen preparation and  
SEM analysis

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